

**Notice of References Cited**

Application/Control No.

10/020,577

Applicant(s)/Patent Under  
Reexamination  
HANAI ET AL.

Examiner

Phi D A

Art Unit

3637

Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5799450	09-1998	Sammon et al	52/208
	B	US-4894972	01-1990	Endoh et al	52/716.1
	C	US-5197243	03-1993	Mozawa et al	52/208
	D	US-6485082	11-2002	Campfield et al	296/95.1
	E	US-5635281	06-1997	Agrawal	428/192
	F	US-5887393	03-1999	Vanark et al	52/208
	G	US-5915780	06-1999	Kobrehel et al	296/146.15
	H	US-2733789	02-1956	Tolle	52/208
	I	US-5339584	08-1994	Ohtake et al	52/208
	J	US-			
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	21749	01-1991	Japan		52/208
	O	60087	02-1992	Japan		52/716.1
	P	70485	03-1992	Japan		52/208
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.